

Title (en)  
MAGNETRON SPUTTERING APPARATUS FOR COMPOUND THIN FILMS

Title (de)  
MIKROWELLENSPUTTERVORRICHTUNG ZUR HERSTELLUNG DÜNNER KOMPOSITFILME

Title (fr)  
APPAREIL DE PULVERISATION AU MAGNETRON DE FILMS MINCES COMPOSITES

Publication  
**EP 0740710 B1 20030402 (EN)**

Application  
**EP 95903531 A 19941130**

Priority  
• US 9413117 W 19941130  
• US 16259293 A 19931206

Abstract (en)  
[origin: US5405517A] An apparatus is described for depositing a thin film (9) of compound materials on selected substrates (48) in an evacuable coating chamber. This apparatus includes a rotating primary surrogate magnetron cathode surface (19) which acts to receive, in-situ, material to be sputtered. Vapor crucibles (2) expose the rotating cathode surface (19) to material vapors (8) which condense on the thermally cooled cathode surface (19) to combine with other coatings on the cathode and are thence rotated through the associated plasma sputter zone (26P) to sputter deposit desired film (9). Auxiliary rotating magnetron cathodes (32) can deposit additional material onto rotating primary cathode (19). Molten material crucible assemblies (31) having coating rollers (34) can convey molten material onto rotating auxiliary thermally cooled cathode surfaces (32) which sputter coat primary cathode. When a selected combination of vapor crucibles (2) and auxiliary rotating cathodes (32) cooperate to coat rotating primary cathode surface (19) it is possible to deposit alloys or a large class of compound thin film materials in-situ without having to prefabricate cathodes of compound materials. Sputter deposited film (9) uniformity is improved by use of three methods: cyclically varying power applied to the primary surrogate cathode, narrow sputter zones, and premixing of condensing vapors.

IPC 1-7  
**C23C 14/34**; **H01J 37/34**

IPC 8 full level  
**C23C 14/34** (2006.01); **C23C 14/35** (2006.01); **C23C 14/56** (2006.01); **H01J 37/34** (2006.01)

CPC (source: EP US)  
**C23C 14/3414** (2013.01 - EP US); **C23C 14/35** (2013.01 - EP US); **C23C 14/562** (2013.01 - EP US); **H01J 37/3402** (2013.01 - EP US); **H01J 37/3429** (2013.01 - EP US); **H01J 37/3432** (2013.01 - EP US)

Citation (examination)  
JP H04210470 A 19920731 - MITSUBISHI MATERIALS CORP

Cited by  
US7842355B2

Designated contracting state (EPC)  
DE FR GB

DOCDB simple family (publication)  
**US 5405517 A 19950411**; DE 69432433 D1 20030508; EP 0740710 A1 19961106; EP 0740710 A4 19980701; EP 0740710 B1 20030402; WO 9516058 A1 19950615

DOCDB simple family (application)  
**US 16259293 A 19931206**; DE 69432433 T 19941130; EP 95903531 A 19941130; US 9413117 W 19941130